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APPLICANTS

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**** CONTINUING DATA *******
 This application is a DIV of 09/884,993 06/21/2001 PAT 6,623,798 ✓ *Ku 11/5/04*

**** FOREIGN APPLICATIONS *******
 REPUBLIC OF KOREA 2000-34485 06/22/2000 ✓ *Ku 11/5/04*

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Foreign Priority claimed 35 USC 119 (a-d) conditions met Verified and Acknowledged	<input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input checked="" type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> Met after Allowance <i>[Signature]</i> Examiner's Signature	STATE OR COUNTRY KOREA, REPUBLIC OF	SHEETS DRAWING 3	TOTAL CLAIMS 6	INDEPENDENT CLAIMS 1
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TITLE
 Chemical vapor deposition method for depositing silicide and apparatus for performing the same